

Receipt

DOCKET NUMBER: 212655US2/pmh

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:  
Masayuki NAKANO, et al.

: GROUP: 1756

SERIAL NUMBER: 09/928,409

: ATTENTION:  
Application Division  
Customer Corrections

FILED: AUGUST 14, 2001

FOR: SUBSTRATE PROCESSING METHOD AND SUBSTRATE PROCESSING  
APPARATUS

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT

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Sir:

The Patent Office is requested to provide a corrected Official Filing Receipt for the attached. If you have any questions, please do not hesitate to contact us.

No fees are required. However, in the event that a fee is required, please charge the appropriate amount to our Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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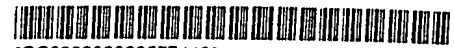


APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/928,409	08/14/2001	1756	1112	212655US2	10	29	6

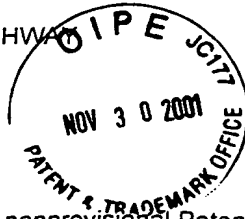
CONFIRMATION NO. 7316

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## FILING RECEIPT



\*OC000000006577440\*



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Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

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## Assignment For Published Patent Application

TOKYO ELECTRON LIMITED, Minato-To, JAPAN;

## Domestic Priority data as claimed by applicant

## Foreign Applications

JAPAN 2000-246223 08/15/2000

If Required, Foreign Filing License Granted 09/18/2001

Projected Publication Date: 02/21/2002

Non-Publication Request: No

Early Publication Request: No

## Title

Substrate processing method and substrate processing apparatus

## Preliminary Class

430

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